Ni(P) Pre/Post Measurement sites

Operations Procedure

Steps:

\*Done for both PRE and POST Ni(P) plating.

1. Move stage to Load/Unload position.
   1. Do this by clicking “Move XY stage to exchange sample” under the **Observation** Menu bar dropdown.
2. Load wafer. Orient notch to line up with the red mark on the stage.
   1. Rotate the stage so that the notch is pointing down.
3. Now click the “Move to origin” on the popup window.
4. Click “OK” on the popup window to move the optics to the reference Z position.
5. Click the “Auto create map” button.
   1. It is good practice to clear the old map first by clicking “Delete map” first.
6. Once complete the last ADM array viewed will be the first measure site.
7. Center the ADM array in the viewport and set an appropriate objective.
8. Click 3D Acquisition.
   1. This may take a moment.
9. Once the newly created 3D/2D Intensity, Height, and Color maps are created click “Analysis”.
   1. This is only open if the Analysis software is open.
10. The first thing you want to do it clean up the maps.
    1. Click Auto Clean, De-Noise, and Tilt.
11. Now select “Profile” in the top tool bar.
12. Measure a horizontal line across the ADM array.
13. Use a Pt. to Pt. Height tool and measure the step height from one of the interconnects to the field.
14. Create a Report and save it under the appropriate project folder.
15. Next we need to measure the ASML site.
16. To find this lower the scope objective back to 5X and move down until you see a horizontal kerf.
17. Once at the kerf move to the left until you see a rectangular box with a series of bars inside it.
18. We are interested in the right side group of bars in the rectangle.
19. Center the group in your viewport and set an appropriate objective.
20. Repeat steps 8-14 for the ASML site.